AMENDMENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

icants:

Y. Granik et al.

Attorney Docket No.: MEGC117332

Application No.: 09/898,431

Group Art Unit: 2123

Filed:

July 2, 2001

Examiner: M.C. Hogan

Title:

METHOD OF COMPENSATING FOR ETCH EFFECTS IN

PHOTOLITHOGRAPHIC PROCESSING

AMENDMENT

Seattle, Washington 98101

May 19, 2005

TO THE COMMISSIONER FOR PATENTS:

INTRODUCTORY COMMENTS

Please amend the above-identified application as follows.